IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):

John W. Jacobs and Elizabeth A. Dauch

Assignee:

NEC Electronics America, Inc.

Title:

TUNGSTEN PLUG CORROSION PREVENTION METHOD

USING GAS SPARGED WATER

Application No.:

Unassigned

Filing Date:

Herewith

Examiner:

Unassigned

Group Art Unit:

Unassigned

Docket No.:

NEC0253US

Austin, Texas October 28, 2003

MAIL STOP PATENT APPLICATION COMMISSIONER FOR PATENTS P. O. BOX 1450 ALEXANDRIA, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT 37 CFR § 1.97(b)

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying PTO Form-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Citation of these documents shall not be construed as:

- 1. an admission that the documents are necessarily prior art with respect to the instant invention;
- 2. a representation that a search has been made; or
- 3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

EXPRESS MAIL NUMBER:

EV 304 737 514 US

Respectfully submitted,

Eric A. Stephenson

Attorney for Applicant(s)

Reg. No. 38,321

U.S. Department of Commerce, Patent and Trademark Office NEC0253US Unassigned				· · · · · · · · · · · · · · · · · · ·						
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